



Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-332001	Application No. 10/659,060
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR 1.98(b))		Applicant Peter J. de Groot	
		Filing Date September 9, 2003	Group Art Unit 2877

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
mjd	AA	4,999,014	03/12/1991	Gold et al.	356	382	
mjd	AB	5,133,601	07/28/1992	Cohen et al.	356	359	
mjd	AC	5,602,643	02/11/1997	Barrett	356	360	
mjd	AD	6,545,763	04/08/2003	Kim et al.	356	503	
mjd	AE	6,597,460	07/22/2003	Groot et al.	356	512	
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AH							
	AI							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
mjd	AJ	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
mjd	AK	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
mjd	AL	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
mjd	AM	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
mjd	AN	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'echelle (sub)micrometrique par microscopie optique interferometrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
mjd	AO	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
mjd	AP	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)
mjd	AQ	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
mjd	AR	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)

Examiner Signature <i>Maurice J. Detsch</i>	Date Considered 9-19-05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-332001	Application No. 10/659,060
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Peter J. de Groot	
		Filing Date September 9, 2003	Group Art Unit 2877

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
mgd	AA	4,576,479	03/18/1986	Downs	356	351	
	AB						
	AC						
	AD						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
mgd	AE	0 397 388 A2	11/14/1990	EPO	G01B	11/06		
mgd	AF	0 549 166 A2	06/30/1993	EPO	G01B	11/06		
	AG							
	AH							
	AI							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AJ	
	AK	
	AL	
	AM	

Examiner Signature <i>Maurissa G. J. [Signature]</i>	Date Considered 9-19-05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	